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PATENT APPLICATION 10/044,076

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

H. Ufuk Alpay et al.

Serial No.:

10/044,076

Date Filed:

January 11, 2002

Group Art Unit:

1756

Examiner:

Mohamedulla, Saleha R.

Title:

DAMAGE RESISTANT PHOTOMASK

CONSTRUCTION

MAIL STOP – AF Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 I hereby certify that this correspondence is being deposited with the United States Postal Service as Express Mail No. EV351292059US addressed to: Mail Stop – AF, Commissioner of Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on July 2, 2004.

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION

In response to the Final Office Action mailed May 5, 2004, Applicants respectfully submit the following amendments set forth below and request favorable action thereon.

Amendments to Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 7 of this paper.